L Number	Hits	Search Text	DB	Time stamp
1	892	( Control of Oping to Or Pull of	USPAT;	2003/12/23 11:15
		ultrapure) near3 (water)) and (water with	US-PGPUB;	
		(low near2 (resistance or resistivity)))	EPO; JPO;	
			DERWENT;	
			IBM_TDB	
2	140	((wash\$3 or clean\$3 or spray\$3 or pure or	USPAT;	2003/12/23 11:28
		ultrapure) near3 (water)) same (water with	US-PGPUB;	
		(low near2 (resistance or resistivity)))	EPO; JPO;	
			DERWENT;	
			IBM_TDB	
3	9	((wash\$3 or clean\$3) with (pure or	USPAT;	2003/12/23 11:29
		ultrapure) near3 (water)) same (water with	US-PGPUB;	
		(low near2 (resistance or resistivity)))	EPO; JPO;	
			DERWENT;	
			IBM TDB	]
4	240		USPAT;	2003/12/23 11:30
		ultrapure) near3 (water)) same (water	US-PGPUB;	
		near3 ((resistance or resistivity)))	EPO; JPO;	
			DERWENT;	
_			IBM_TDB	
5	23	((wash\$3 or clean\$3) with (pure or	USPAT;	2003/12/23 11:30
		ultrapure) near3 (water)) same (water	US-PGPUB;	1
		near3 ((resistance or resistivity))) same	EPO; JPO;	
		(dust or static)	DERWENT;	İ
			IBM_TDB	
-	204	(Munakata.in. or (Shin adj Etsu).as.) and	USPĀT;	2003/12/22 15:22
		((coat\$3 or surfactant or dip or dipped or	US-PGPUB;	
		dipping or immers\$4 or submer\$5 or	EPO; JPO;	
		deposit\$3 or film or layer) with ((wafer	DERWENT;	
		or chip or substrate or disc or disk)	IBM_TDB	1
		near3 (storage or storing or case or box	_	
		or holder or holding or housing or		
		carrier)))		
-	177	(Munakata.in. or (Shin adj Etsu).as.) and	USPAT;	2003/12/22 15:05
		((coat\$3 or surfactant or dip or dipped or	US-PGPUB;	
		dipping or immers\$4 or submer\$5 or	EPO; JPO;	
		deposit\$3 or film or layer) with ((wafer	DERWENT:	
		or chip or substrate or disc or disk)	IBM_TDB	
		near3 (storage or storing or case or box		
		or holding or housing or carrier)))		
-	2	(Munakata.in. or (Shin adj Etsu).as.) and	USPAT;	2003/12/22 14:55
İ		((coat\$3 or dip or dipped or dipping or	US-PGPUB;	
		immers\$4 or submer\$5 or deposit\$3 or film	EPO; JPO;	
		or layer) with ((wafer or chip or	DERWENT;	
		substrate or disc or disk) near3 (storage	IBM_TDB	
		or storing or case or box or holding or	_	
ļ		housing or carrier)) with surfactant)		
-	40	(Munakata.in. or (Shin adj Etsu).as.) and	USPAT;	2003/12/22 14:56
İ		((coat\$3 or surfactant or dip or dipped or	US-PGPUB;	
		dipping or immers\$4 or submer\$5 or	EPO; JPO;	
		deposit\$3 or film or layer) with ((wafer	DERWENT;	
		or chip or substrate or disc or disk)	IBM_TDB	
ŀ		near3 (storage or storing or case or box		
1		or holding or housing or carrier))) same		
İ		(dust\$3 or particle or particulate or		
		contamin\$8)		1

Second Comparison of Chinn and Estan as, and clapsing or immersal or submers 5 or deposited or film or layer) with ((wafer or chip or substrate or disc or disk)   DERWING   D						
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deposits3 or film or layer) with (wafer or chip or substrate or disc or disc) and content of the	ļ			((coat\$3 or surfactant or dip or dipped or		, , == == == == == == == == == == == ==
Or chip or substrate or disk or disk)  Rear3 (storage or storing or case or box or helding or housing or carrier()) same (for contamins8) pricele or particulate or in adj Etau).as.) and ((coat8) or dip or dipped or dipping or immers84 or submer85 or deposit30 or film or layer) with ((wafer or chip or substrate or diac or disk) near3 (storage or storing or case or box or holding or housing or carrier()) with maurfactant))  137  (Goat83 or surfactant or dip or dipped or dipping or immers84 or submer85 or dipping or immers84 or submer85 or or holding or housing or carrier()) ((Munakata.in. or (Shin adj Etau).as.) and ((coat83 or surfactant or dip or dipped or deposit33 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier())) same (dust33 or particle or particulate or or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier()) same (dust33 or particle or particulate or or chip or substrate or disc or disk) near3 (casestely))  ((Munakata.in. or (Shin adj Etau).as.) and ((coat83 or surfactant or dip or dipped or deposit33 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (casestely))  ((Munakata.in. or (Shin adj Etau).as.) and ((coat83 or surfactant or dip or dipped or dipping or immers84 or submer85 or deposit33 or film or layer) with ((wafer or chip or substrate or disc or disk)  rear3 (casestely))  ((Munakata.in. or dip or dipped or dipping or immers84 or submer85 or deposit33 or film or layer) with (wafer or chip or substrate or disc or disk)  rear3 (casestre))  ((Shin adj Etau).as.) and (coat83 or substrate or disc or disk)  rear3 (casestre))  ((Shin adj Etau).as.) and (coat83 or substrate or disc or disk)  rear4 (casestre))  ((Shin adj Etau).as.) and (coat83 or substrate or disc or disk)  rear5 (casestre))  ((Shin adj Etau).as.) and (coat83 or substrate or disc or disk)  rear6 (casestre))  ((Shin adj Etau).as.) and (coat83 or substrate or disc	1			deposits or film on leven with a		
Tear's (storage or storing or case or box or holding or housing or carrier)) same (dust's) or particulate or contaminate) not ((Munakta.in. or (Shin as in contaminate)) not ((Munakta.in. or (Shin as in contaminate)) and ((coat's) or dip or dipped or dippid or dipped or dippid or dipped or dippid or dipped or disping or immers's or box or holding or housing or carrier))				or chip or substrate or disc or disch	,	
Or holding or housing or carrier;)) same (dust\$3 or particle or particulate or contamins8)) not ((Munakata.in. or (Shin adj Etau).as.) and ((coat\$3 or dipping or immers\$4 or submer\$5 or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with or disk, near3 (storage or storing or case or box or holding or housing or carrier))  137 ((Munakata.in. or (Shin adj Etau).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box of (munakata or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier!)) same (dust\$3 or particle or particulate or chip or substrate or disc or disk) near3 (storage or storing or carrier); same (dust\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or or chip or substrate or disc or disk) near3 (coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (coat\$3 or surfactant or dip or dipping or immers\$4 or submer\$5 or dipping or immer\$4 or submer\$5 or substrate or disc or disk) near3 (coat\$3 or surfactant or dip or dipping or immer\$4 or submer\$5 or dipping or immer\$4 or submer\$5 or dipping or immer\$4 or submer\$5 or dipping or immer\$4 or submer\$5 or dipping or immer\$4 or submer\$5 or dipping or immer\$4 or submer\$5 or dipping or immer\$4 or submer\$5 or dipping or immer\$4 or submer\$5 or dipping or immer\$4 or submer\$5 or dipping or immer\$4 or submer\$5 or dipping or immer\$4				near3 (storage or storing or case or how	L TRM T.DB	
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adj Btsu).as.) and ((coat\$3 or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) nean3 (storage or storing or case or disk) nean3 (storage or storing or case or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) nean3 (storage or storing or case or box or holding or housing or carrier))) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc) disk) nean3 (storage or storing or case or box or holding or storing or case or box or holding or substrate or disc or disk) near3 (casasette))  1 2 (Wunakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (casasette))  9 ((Munakata.in. or submer\$5 or deposit\$3 or film or layer) with ((wafer or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or case or box or holding or housing or case or box or holding or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or layer) with ((wafer or chip or dipped or				contamin\$8)) not ((Munakata.in. or (Shin		
disped or disping or immers84 or submers5 or deposits3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))  with surfactant))  137 ((Monakata.in.or (Shin adj Etsu).as.) and ((Monakata.in.or substrate or disped or disposits3 or film or layer) with ((wafer or chip or substrate or disposits3 or film or layer) with ((wafer or chip or substrate)) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coats3 or surfactant or dip or disped or disping or immers84 or submers5 or deposits3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust3) or particula or particulate or contamins3)  12 (Munakata.in. or (Shin adj Etsu).as.) and ((coats3 or surfactant or dip or dipped or dipping or immers84 or submers5 or deposits3 or film or layer) with ((wafer or chip or surfactant or dip or dipped or dipping or immers84 or submers5 or deposits3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (casestel)) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coats3 or surfactant or dip or dipped or dipping or immers84 or submers5 or deposits3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (casestel)) not (((Munakata.in. or (Shin adj Etsu).as.) and (coats3 or surfactant or dip or dipped or dipping or immers84 or submers5 or deposits3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (casetal) or or particulate or dipped or dipping or immers84 or submers5 or deposits3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (casetant or dip or dipped or				adj Etsu).as.) and ((coat\$3 or dip or		
or deposits3 or film or layer) with  ((wafer or or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))  with surfactant)  137 ((Munakata.in. or (Shin adj Etsu).as.) and (coat3) or surfactant or dip or dipped or dipping or immers34 or submer\$5 or or disk)  near3 (storage or storing or case or box or holding or housing or carrier)) mot ((Munakata.in. or (Shin adj Etsu).as.) and ((coat3) or surfactant or dip or dipped or dipping or immers4 or submer\$5 or deposits3 or film or layer) with ((wafer or chip or substrate or disc or disk)  near3 (storage or storing or case or box or holding or housing or carrier)) some (dust3) or surfactant or dip or dipped or dipping or immers4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk)  near3 (cassatte))  12 (Munakata.in. or (Shin adj Etsu).as.) and ((coat3) or surfactant or dip or dipped or dipping or immers4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk)  near3 (cassatte))) (or (Shin adj Etsu).as.) and ((coat3) or surfactant or dip or dipped or dipping or immers4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk)  near3 (cassatte))) (not ((Munakata.in. or (Shin adj Etsu).as.)) and ((coat3) or substrate or disc or disk)  near3 (cassatte))) (not ((Munakata.in. or (Shin adj Etsu).as.)) and ((coat3) or substrate or dip or dipping or immers4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or dip or dipping or immer\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or dip or dipping or immer\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust3)  19 (Munakata.in. or (Shin adj Etsu).as.) and (coat3) or surfactant or dip or dipped or dipping or immer\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or				dipped or dipping or immers\$4 or submer\$5		1
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deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (cassette))) ) not (((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8))) (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6))) (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				((Coat\$3 or surfactant or dip or dipped or		
or chip or substrate or disc or disk) near3 (cassette))) not (((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8))) (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6))) (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				deposited or film on leave to the		
near3 (cassette))) ) not (((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) ) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipping or substrate or disc or disk) near3 (storage or storing or case or box or holding or nousing or carrier))) same (dust\$3 or surfactant or dip or dipping or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8))) (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6)))  896 (427/330,235).CCLS.  806 (427/352,353,354).CCLS.  1				or chip or substrate or disc an disk		
or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8))) (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6))) (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT;				near3 (cassette))) ) not ((Munnkata in	IBM_TDB	
surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) ) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8)))  (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6)))  896 (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				or (Shin add Etsu) as ) and //coats3 on	İ	
lmmers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) ) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8))) (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6)) (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  806 (427/372,2,370,384).CCLS.  3616 (427/372,2,370,384).CCLS.  3616 (427/372,2,370,384).CCLS.	ĺ			surfactant or dip or dipped or dipping or		
or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) ) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8)) (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6)) (427/230,235).CCLS.  896 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				immers\$4 or submer\$5 or deposit\$3 or film		
substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8)))  (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6))  896 (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  3616 (427/372 2 270 284) CCLS.  USPAT; USPGPUB	İ			or layer) with ((wafer or chip or		
or storing or case or box or holding or housing or carrier))) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8)))  ((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6)))  (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				substrate or disc or disk) near3 (storage		
housing or carrier))) ) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8))) (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6)) (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				or storing or case or box or holding or		1
or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8))) (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6))) (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				housing or carrier))) ) not ((Munakata in		j
<pre>1mmers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8))) (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6))) (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB</pre>	1			or (Shin adj Etsu).as.) and ((coat\$3 or		
or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8))) (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6)))  896 (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  807 (427/372,2,270,384).CCLS.  808 (427/372,2,270,384).CCLS.				surfactant or dip or dipped or dipping or		
substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8))) (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6))) (427/230,235).CCLS.  896 (427/352,353,354).CCLS.  806 (427/372,2,270,384).CCLS.  19 USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				or layer) with (/wwf.		
or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8)))  (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk)  near3 (transport\$6)))  (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				variate or disc or disc or disc.		
housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8))) (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6))) (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				or storing or case or how on halding		
particle or particulate or contamin\$8))) (Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6))) (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				housing or carrier))) same /dustee and		
(Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6)))  (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB		-		particle or particulate or contamingous		1
((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6)))  896 (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB		İ	19	(Munakata.in. or (Shin adi Etsu) as ) and	HQDAT.	2002/10/20 25 22
dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6)))  896 (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  108 PO; JPO; DERWENT; IBM TDB  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				[ { (Coat\$3 or surfactant or dip or dipped or ]		2003/12/22 15:08
deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk)  near3 (transport\$6)))  (427/230,235).CCLS.  B06 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB				dipping or immers\$4 or submer\$5 or		1
or chip or substrate or disc or disk) near3 (transport\$6))) (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB	1			deposit\$3 or film or laver) with ((wafer		
near3 (transport\$6))) (427/230,235).CCLS.  806 (427/352,353,354).CCLS.  USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB		1		or chip or substrate or disc or disk)	•	]
806 (427/352,353,354).CCLS. US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB			000	near3 (transport\$6)))	<u>-</u>	
- 806 (427/352,353,354).CCLS. US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB	] -		896	(42//230,235).CCLS.	USPAT;	2003/12/22 15:08
- 3616 (427/372 2 270 294) CCLG	_		80 <i>6</i>	(427/252 252 254) 2272	US-PGPUB	
1			808	(427/332,353,354).CCLS.		2003/12/22 15:08
USPAT:   2003/12/22 15.08	-		3616	(427/372.2.379.384) core		
			300	(12,70,2,2,019,004).CCIS.	USPAT;	2003/12/22 15:08
US-PGPUB US-PGPUB					US-PGPUB	

_	1369	(427/430.1).CCLS.	T COD D CO	
_	212		USPAT; US-PGPUB	2003/12/22 15:09
_	717		USPAT; US-PGPUB	2003/12/22 15:09
	2870	(CLS.	USPAT; US-PGPUB	2003/12/22 15:09
-	517	(206/524.3).CCLS.	USPAT; US-PGPUB	2003/12/22 15:09
_	10391	((427/230,235).CCLS.) ((427/352,353,354).CCLS.) ((427/372.2,379,384).CCLS.)	USPAT; US-PGPUB	2003/12/22 15:14
_	16	((427/430.1).CCLS.) ((438/125).CCLS.) ((206/308.1,524.1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.)	USPAT; US-PGPUB	2003/12/22 15:12
_	0	((206/524.3).CCLS.) and ((wafer or semiconductor) same (surfactant))	USPAT; US-PGPUB	2003/12/22 15:11
_	40	((206/524.3).CCLS.) and ((surfactant))	USPAT;	2003/12/22 15:12
_	0	(((206/524.3).CCLS.) and ((surfactant))) and (wafer or semiconductor)	US-PGPUB USPAT;	2003/12/22 15:12
_	402	(((427/230,235).CCLS.) ((427/352,353,354).CCLS.) ((427/372.2,379,384).CCLS.)	US-PGPUB USPAT; US-PGPUB	2003/12/22 15:14
_		((427/430.1).CCLS.) ((438/125).CCLS.) ((206/308.1,524.1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.)) and ((coat\$3 or deposit\$3 or film or layer or immers\$5 or soak\$3 or dip or dipped or dipping or submer\$8) with surfactant) ((((427/230,235).CCLS.) ((427/352,353,354).CCLS.) ((427/372.2,379,384).CCLS.) ((427/430.1).CCLS.) ((438/125).CCLS.) ((206/308.1,524.1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.)) and ((coat\$3 or deposit\$3 or film or layer or immers\$5 or soak\$3 or dip or dipped or dipping or submer\$8) with surfactant)) and (dust\$3 or particle or particulate or contamin\$8)	USPAT; US-PGPUB	2003/12/22 15:15
	140	((((427/230,235).CCLS.) ((427/352,353,354).CCLS.) ((427/372.2,379,384).CCLS.) ((427/430.1).CCLS.) ((438/125).CCLS.) ((206/308.1,524.1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.)) and ((coat\$3 or deposit\$3 or film or layer or immers\$5 or soak\$3 or dip or dipped or dipping or submer\$8) with surfactant)) and (dust\$3 or contamin\$8)	USPAT; US-PGPUB	2003/12/22 15:15
	42	((((427/230,235).CCLS.) ((427/352,353,354).CCLS.) ((427/372.2,379,384).CCLS.) ((427/430.1).CCLS.) ((438/125).CCLS.)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/12/22 15:20

-	7	((206/524.3).CCLS.) and (((wafer or chip	USPAT;	2003/12/22 15:21
İ		or substrate or disc or disk) near3	US-PGPUB;	
		(storage or storing or case or box or	EPO; JPO;	
		holder or holding or housing or carrier or	DERWENT;	Į.
		cassette or transport\$6)))	IBM_TDB	
_	439	( ( ( ) = - / = 0 ) = 0 = 20 ; (	USPAT;	2003/12/22 15:51
		((427/352,353,354).CCLS.)	US-PGPUB	
		((427/372.2,379,384).CCLs.)		
		((427/430.1).CCLS.) ((438/125).CCLS.)	-	
		((206/308.1,524.1,524.6,525,526,832).CCLS.)	ĺ	
		((206/524.3).CCLS.)) and ((coat\$3 or		
		surfactant or dip or dipped or dipping or		
		immers\$4 or submer\$5 or deposit\$3 or film		
		or layer) with ((wafer or chip or		
		substrate or disc or disk) near3 (storage		
		or storing or case or box or holder or		
i _		holding or housing or carrier)))		
	71	((((()))))	USPAT;	2003/12/22 15:24
		((427/352,353,354).CCLS.)	US-PGPUB	j
		((427/372.2,379,384).CCLS.)		
		((427/430.1).CCLS.) ((438/125).CCLS.)		
		((206/308.1,524.1,524.6,525,526,832).CCLS.)		
		((206/524.3).CCLS.)) and ((coat\$3 or		
-	1	surfactant or dip or dipped or dipping or		
İ		immers\$4 or submer\$5 or deposit\$3 or film		
		or layer) with ((wafer or chip or		
		substrate or disc or disk) near3 (storage		
		or storing or case or box or holder or		
		holding or housing or carrier)))) and		
		((prevent\$5 or eliminat\$5 or reduc\$6 or		
		lower\$3 or stop\$4) near3 (dust\$3 or		
	255	particle or particulate or contamin\$8))		
-	255	(((427/230,235).CCLS.)	USPAT;	2003/12/22 15:35
		((427/352,353,354).CCLS.)	US-PGPUB	
		((427/372.2,379,384).CCLS.)		
		((427/430.1).CCLS.) ((438/125).CCLS.)		
		((206/308.1,524.1,524.6,525,526,832).CCLS.)		
		((206/524.3).CCLS.)) and ((coat\$3 or		
		surfactant or dip or dipped or dipping or		
		immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or		
		substrate or disc or disk) near2 (storage		l
1		or storing or how or holder or helder		
İ		or storing or box or holder or holding or housing or carrier or cartridge)))		
_	211	((((427/230,235).CCLS.)		
	211	((427/352,353,354).CCLS.)	USPAT;	2003/12/22 15:29
	[	((427/372.2,379,384).CCLS.)	US-PGPUB	ĺ
		((427/430.1).CCLS.) ((438/125).CCLS.)		
		(1206/308 1 524 1 524 6 525 526 922) cord vi		
		((206/308.1,524.1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.)) and ((coat\$3 or		ļ
		surfactant or dip or dipped or dipping or		
	ĺ	immers\$4 or submer\$5 or deposit\$3 or film		
		or layer) with ((wafer or chip or		ĺ
		substrate or disc or disk) near2 (storage		
		or storing or box or holder or holding or		
	j	housing or carrier or cartridge)))) not		
		(((((427/230,235).CCLS.)		İ
		((427/352,353,354).CCLS.)		
		((427/372.2,379,384).CCLS.)	i	
		((427/430.1).CCLS.) ((438/125).CCLS.)		
	1	((206/308.1,524.1,524.6,525,526,832).CCLS.)		
		((206/524.3).CCLS.)) and ((coat\$3 or		İ
]		surfactant or dip or dipped or dipping or		
1		immers\$4 or submer\$5 or deposit\$3 or film	İ	
	i	or layer) with ((wafer or chip or		
		substrate or disc or disk) near3 (storage		
]	l	or storing or case or box or holder or	ļ	
1		holding or housing or carrier)))) and		
	j	((prevent\$5 or eliminat\$5 or reduc\$6 or		
[	ĺ	lower\$3 or stop\$4) near3 (dust\$3 or		
		particle or particulate or contamin\$8)))	ļ	
·		- The Property of Contountary (1)		

-	129	I The second of cooking and the thirty	EPO; JPO;	2003/12/22 15:48
		chip or substrate or disc or disk) near2	DERWENT;	
		(storage or storing or box or holder or	IBM_TDB	
	ĺ	holding or housing or carrier or cartridge or case)))		
_	96		EPO; JPO;	2002/10/00 15:20
]		chip or substrate or disc or disk) near2	DERWENT;	2003/12/22 15:38
		(storage or storing or box or holder or	IBM TDB	
		holding or housing or carrier or cartridge		
		or case))) ) and (coat\$3 or wash\$3 or		
		clean\$3 or film or layer or deposit\$3 or		
		immers\$5 or submer\$6 or soak\$3 or dip or		
	2.5	dipped or dipping)		
~	33		EPO; JPO;	2003/12/22 15:48
		chip or substrate or disc or disk) near2	DERWENT;	
		(storage or storing or box or holder or	IBM_TDB	
		holding or housing or carrier or cartridge or case))) ) not (((surfactant or scourol)		
		and (((wafer or chip or substrate or disc		
		or disk) near2 (storage or storing or box		
		or holder or holding or housing or carrier		
į į		or cartridge or case)))) and (coat\$3 or	İ	
ĺ	•	wash\$3 or clean\$3 or film or layer or		
		deposit\$3 or immers\$5 or submer\$6 or		
		soak\$3 or dip or dipped or dipping))		
-	178	((coat\$3 or dip or dipped or dipping or	USPAT;	2003/12/22 16:03
ĺ		immers\$4 or submer\$5 or deposit\$3 or film	US-PGPUB	
		or layer) same ((wafer or chip or		
		substrate or disc or disk) near3 (storage		
	I	or storing or case or box or holder or holding or housing or carrier))) same		
		(surfactant or scourol)		
-	245		USPAT;	2003/12/22 15:53
		immers\$4 or submer\$5 or deposit\$3 or film	US-PGPUB	2003/12/22 13:53
		or layer or wash\$3 or clean\$3) same	00 10100	
		((wafer or chip or substrate or disc or		
		disk) near3 (storage or storing or case or		
		box or holder or holding or housing or		
_	958	carrier))) same (surfactant or scourol)		
	938		USPAT;	2003/12/22 16:20
	i	immers\$4 or submer\$5 or deposit\$3 or film or layer) same ((wafer or chip or	US-PGPUB	
		substrate or disc or disk) near3 (storage		
		or storing or case or box or holder or		
		holding or housing or carrier))) same		
	[	(antistatic\$3 or (anti adj static\$3) or		
		((prevent\$4 or eliminat\$3 or reduc\$5 or		
		stop\$4 or lower\$3) near3 (dust or		
	,,	contamin\$5 or particle or particulate)))		
-	11	(((coat\$3 or dip or dipped or dipping or	USPAT;	2003/12/22 16:05
		immers\$4 or submer\$5 or deposit\$3 or film	US-PGPUB	
		or layer) same ((wafer or chip or substrate or disc or disk) near3 (storage		
		or storing or case or box or holder or		
	ļ	holding or housing or carrier))) same		
	İ	(antistatic\$3 or (anti adj static\$3) or		
		((prevent\$4 or eliminat\$3 or reduc\$5 or		
		stop\$4 or lower\$3) near3 (dust or		
	•	contamin\$5 or particle or particulate))))		
	Ì	and (((427/230,235).CCLS.)		
		((427/352,353,354).CCLs.)		ļ
		((427/372.2,379,384).CCLS.)		
-	i	((427/430.1).CCLS.) ((438/125).CCLS.)		
		((206/308.1,524.1,524.6,525,526,832).CCLS.)		
		((200) 324.3).ССБЗ.//		

Search History

_	38	immers\$4 or submer\$5 or deposit\$3 or film	USPAT; US-PGPUB	2003/12/22 16:12
		or layer) same ((wafer or chip or		
		substrate or disc or disk) near3 ((storage		ĺ
		or storing or holding or housing or		
	}	<pre>transport\$5) near2 (case or box or holder or carrier)))) same (antistatic\$3 or (anti</pre>		
		adj static\$3) or ((prevent\$4 or eliminat\$3		
		or reduc\$5 or stop\$4 or lower\$3) near3		
		(dust or contamin\$5 or particle or	i	
		particulate)))		
-	62	I ( )	USPAT;	2003/12/22 16:19
İ		immers\$4 or submer\$5 or deposit\$3 or film	US-PGPUB	
		or layer) same ((wafer or chip or		
		substrate or disc or disk) near3 ((storage or storing or holding or housing or	1	
		transport\$5) near2 (case or box or holder		
		or carrier)))) and (surfactant)		
-	62	(((coat\$3 or dip or dipped or dipping or	USPAT;	2003/12/22 16:13
	İ	immers\$4 or submer\$5 or deposit\$3 or film	US-PGPUB	2003/12/22 10.13
		or layer) same ((wafer or chip or		
i		substrate or disc or disk) near3 ((storage		
		or storing or holding or housing or		
		transport\$5) near2 (case or box or holder or carrier)))) and (surfactant)) not		
ĺ		((((427/230,235).CCLS.)		
	<b>1</b>	((427/352,353,354).CCLS.)		
		((427/372.2,379,384).CCLS.)		
İ		((427/430.1).CCLS.) ((438/125).CCLS.)		
		((206/308.1,524.1,524.6,525,526,832),CCLS.)		
		((206/524.3).CCLS.)) and ((coat\$3 or		
		surfactant or dip or dipped or dipping or		
		immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or		
İ		substrate or disc or disk) near2 (storage		
		or storing or box or holder or holding or		
-	33389	Mousang3oorcdipier dippedtoiddebbing or	USPAT;	2003/12/22 16:31
İ		immers\$4 or submer\$5 or deposit\$3 or film	US-PGPUB	2003/12/22 10.31
		or layer) with (surfactant))		
-	401	(((coat\$3 or dip or dipped or dipping or	USPAT;	2003/12/22 16:19
		immers\$4 or submer\$5 or deposit\$3 or film	US-PGPUB	
		or layer) with (surfactant)) ) and (((427/230,235).CCLs.)		
		((427/352,353,354).CCLs.)		
		((427/372.2,379,384).CCLS.)		
		((427/430.1).CCLS.) ((438/125).CCLS.)		
		((206/308.1,524.1,524.6,525,526,832).CCLS.)		
		((206/524.3).CCLS.))		
_	0	(((((coat\$3 or dip or dipped or dipping or	USPAT;	2003/12/22 16:22
		<pre>immers\$4 or submer\$5 or deposit\$3 or film or layer) with (surfactant)) ) and</pre>	US-PGPUB	1
		(((427/230,235).CCLS.)		}
	]	((427/352,353,354).CCLS.)		
	1	((427/372.2,379,384).CCLS.)		
		((427/430.1).CCLS.) ((438/125).CCLS.)		
		((206/308.1,524.1,524.6,525,526,832),CCLS.)		
		((206/524.3).CCLS.))) and ((wafer or chip		
		or substrate or disc or disk) near3		
		((storage or storing or holding or housing or transport\$5) near2 (case or box or		
		holder or carrier))))		
	<del></del>			<u>                                       </u>

-	41	1 ( ( man of or other of papaciate of disc of	USPAT;	2003/12/22 16:22
		disk) near3 (storage or storing or case or	US-PGPUB	
		box or holder or holding or housing or	1	
		carrier or cartridge or transport\$8))) and		
		((((coat\$3 or dip or dipped or dipping or		
	i	immers\$4 or submer\$5 or deposit\$3 or film		
		or layer) with (surfactant)) ) and (((427/230,235).CCLS.)		
	-	((427/352,353,354).CCLS.)		i
		((427/372.2,379,384).CCLS.)		
		((427/430.1).CCLS.) ((438/125).CCLS.)		
		((206/308.1,524.1,524.6,525,526,832).CCLS.)		
		((206/524.3).CCLS.)))		
-	2926	(((wafer or chip or substrate or disc or	USPAT;	2003/12/22 16:32
		disk) near3 (storage or storing or case or	US-PGPUB	2003/12/22 16:32
		box or holder or holding or housing or	05 10105	
		carrier or cartridge or transport\$8))) and		
	1	(((coat\$3 or dip or dipped or dipping or		ĺ
		immers\$4 or submer\$5 or deposit\$3 or film		
		or layer) with (surfactant)) )		
-	34	((((coat\$3 or dip or dipped or dipping or	USPAT;	2003/12/22 16:22
		immers\$4 or submer\$5 or deposit\$3 or film	US-PGPUB	1 , 30 , 52 10,22
		or layer) with (surfactant)) ) and ((wafer	[	1
		or chip or substrate or disc or disk)		1
		near3 ((storage or storing or holding or		
		housing or transport\$5) near2 (case or box	ļ	
_	144	or holder or carrier))))		
	144	((coat\$3 or dip or dipped or dipping or	USPAT;	2003/12/22 16:34
		<pre>immers\$4 or submer\$5 or deposit\$3 or film or layer) with (surfactant)) same</pre>	US-PGPUB	
		((prevent\$5 or eliminat\$3 or reduc\$5 or		}
	j	stop\$4 or lower\$3) near3 (dust\$3 or		
		contamin\$8))		
-	7772	((coat\$3 or dip or dipped or dipping or	EDO. TDO.	2002/10/00 16 20
		immers\$4 or submer\$5 or deposit\$3 or film	EPO; JPO; DERWENT;	2003/12/22 16:33
		or layer) near5 (surfactant))	IBM TDB	
-	28	(((coat\$3 or dip or dipped or dipping or	EPO; JPO;	2003/12/22 16:32
		immers\$4 or submer\$5 or deposit\$3 or film	DERWENT;	2003/12/22 10:32
	1	or layer) near5 (surfactant)) ) and	IBM TDB	].
		(((wafer or chip or substrate or disc or		
		disk) near3 (storage or storing or case or		1
		box or holder or holding or housing or		!
	200	carrier or cartridge or transport\$8)))		
_	322	((coat\$3 or dip or dipped or dipping or	EPO; JPO;	2003/12/22 16:34
		immers\$4 or submer\$5 or deposit\$3 or film	DERWENT;	
		or layer) near5 (surfactant)) and (dust\$3	IBM_TDB	j
_	296	or contamin\$8)		
	230	((coat\$3 deposit\$3 or film or layer) near5	EPO; JPO;	2003/12/22 16:39
	j l	(surfactant)) and (dust\$3 or contamin\$8)	DERWENT;	
_	55	((coat\$3 or dip or dipped or dipping or	IBM_TDB	
	55	immers\$4 or submer\$5 or deposit\$3 or film	EPO; JPO;	2003/12/22 16:35
		or layer) near3 (surfactant)) and	DERWENT;	
		((prevent\$5 or eliminat\$3 or reduc\$5 or	IBM_TDB	
		stop\$4 or lower\$3) near3 (dust\$3 or		
		contamin\$8))		
-	47	((coat\$3 deposit\$3 or film or layer) near5	EPO; JPO;	2002/12/22 16:20
		(surfactant)) and (dust\$3 or contamin\$8)	DERWENT;	2003/12/22 16:39
		and dry\$3	IBM TDB	
-	41	(((coat\$3 deposit\$3 or film or layer)	EPO; JPO;	2003/12/23 11:13
		near5 (surfactant)) and (dust\$3 or	DERWENT;	2003/12/23 11:13
		contamin\$8) and dry\$3) not (((coat\$3 or	IBM TDB	
		dip or dipped or dipping or immers\$4 or		'
		submer\$5 or deposit\$3 or film or laver)		
		near3 (surfactant)) and ((prevent\$5 or		
		01:min=400 1 AF 5		1
		eliminat\$3 or reduc\$5 or stop\$4 or lower\$3) near3 (dust\$3 or contamin\$8)) )	i	I